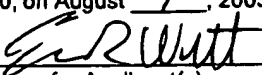




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CERTIFICATE OF MAILING	
I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Mail Stop AF, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450, on August <u>4</u> , 2005.	
 Attorney for Applicant(s)	

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.	:	10/631,134	Confirmation No.:	2470
Applicant	:	Hui-Chu Lin et al.		
Title	:	METHOD FOR IMPROVING FILM UNIFORMITY IN PLASMA ENHANCED CHEMICAL VAPOR DEPOSITION SYSTEM		
Filed	:	July 31, 2003		
TC/A.U.	:	1762		
Examiner	:	Eric B. Fuller		
Docket No.	:	3304.2.75		
Customer No.	:	21552		

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

AMENDMENT AND RESPONSE TO FINAL OFFICE ACTION

Dear Sir:

This paper is filed in response to the Office Action of May 5, 2005. Please amend the above-identified application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 4 of this paper.